

<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>	<b>Docket Number (Optional)</b> <b>TWI-12410</b>		<b>Application Number</b> <b>09/848,733</b>
	<b>Applicant(s)</b> <b>Craig Uhrich et al.</b>		
	<b>Filing Date</b> <b>May 3, 2001</b>		<b>Group Art Unit</b> <b>2877</b>

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE


**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS**

*(Including Author, Title, Date, Pertinent Pages, Etc.)*

DS	CA	M.E. El-Ghazzawi et al., "Spectroellipsometry characterization of directly bonded silicon-on-insulator structures," <i>Thin Solid Films</i> , Vol. 233 (1993), pp. 218-222.

<b>Examiner</b> 	<b>Date Considered</b> 4/21/04
<b>Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</b>	